

Supporting Information

Optical resonance and charge transfer behavior on patterned WO₃
microdisc arrays

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Table S1. Time-resolved photoluminescence (TRPL) emission decay time and abundance of samples for full, green, and blue emission spectra.

		Film			Disc	
Full emission	τ (ns)	0.045	0.251	1.876	0.044	0.332
	Abundance (%)	57.3	42.1	0.6	78.8	21.2
Green Emission	τ (ns)	0.045	0.254	1.819	0.044	0.255
	Abundance (%)	65.2	34.0	0.8	83.9	16.1
Blue Emission	τ (ns)	0.044	0.266	-	0.044	0.239
	Abundance (%)	34.7	65.3	-	59.4	40.6

Figure S1 presents a schematic of the fabrication process of the patterned WO_3 microdisc arrays. The micropatterned arrays of WO_3 were electrochemically deposited on patterned indium tin oxide (ITO) glass, which was prepared using photolithography.

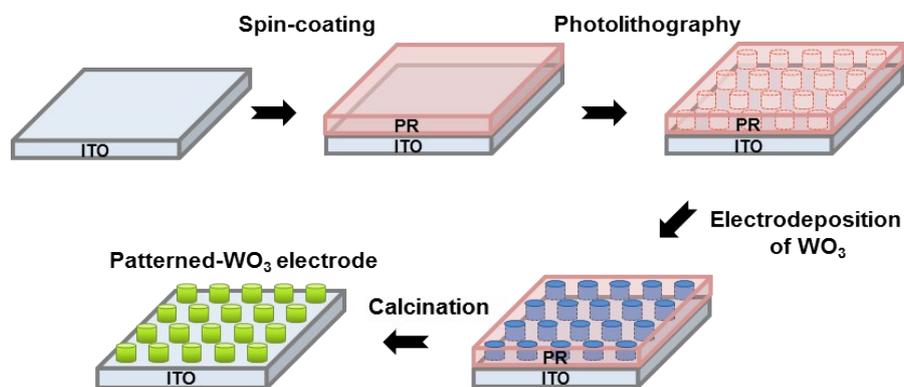


Figure S1. Schematic illustration of fabrication process for the patterned WO_3 microdisc arrays.

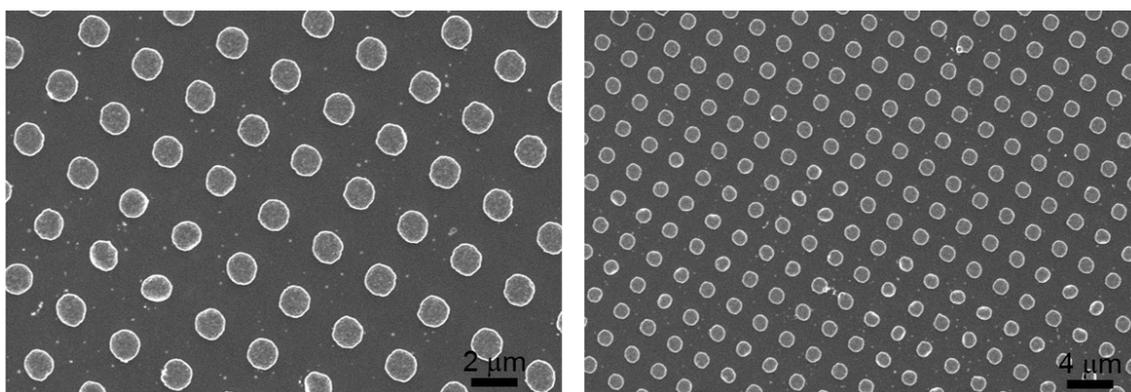
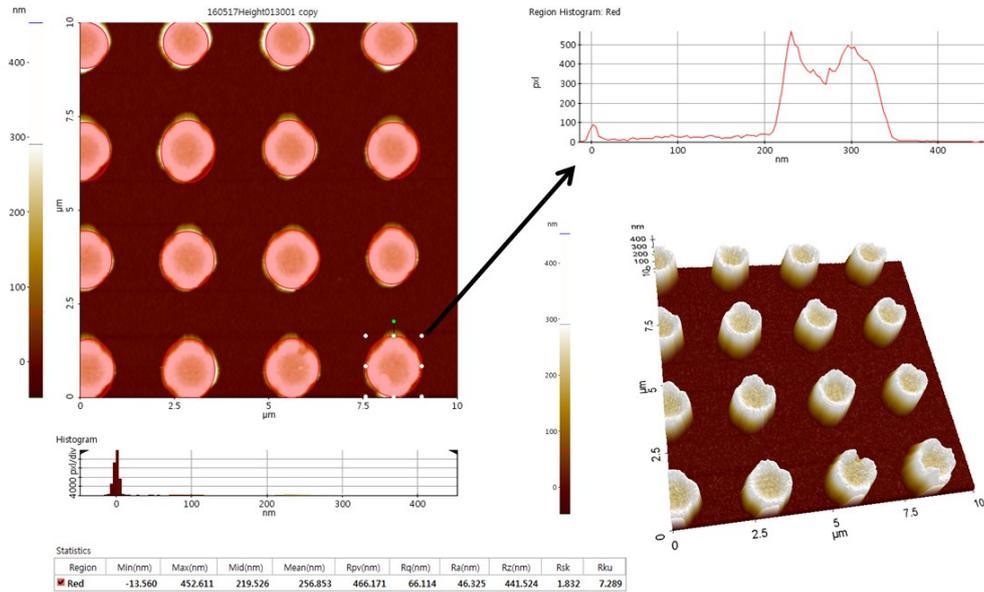


Figure S2. FE-SEM images of WO_3 microdisc arrays electrodeposited on the patterned ITO with 1.5 C of the passed charge.

a) WO₃ microdisc arrays



b) WO₃ film

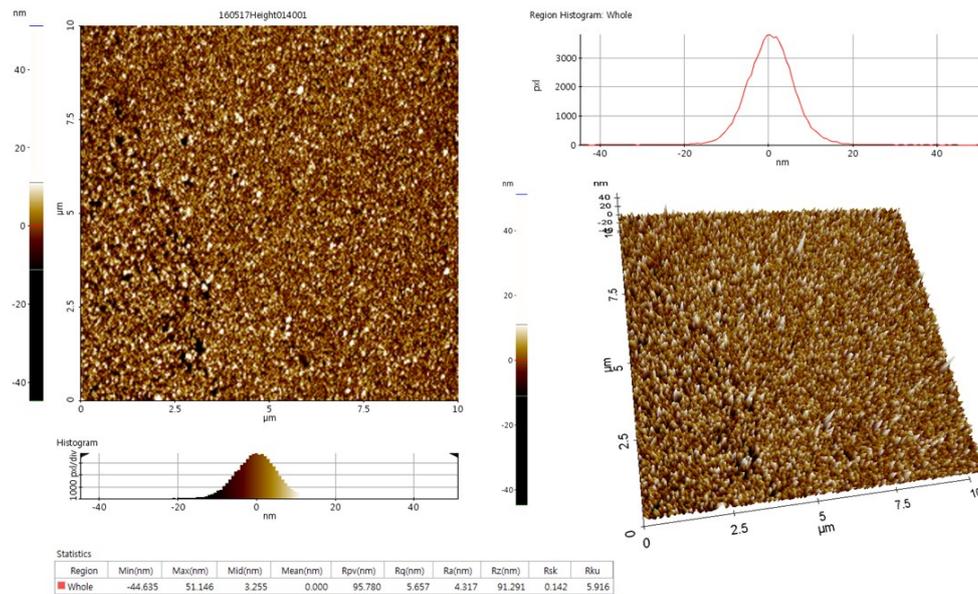


Figure S3. AFM images of (a) WO₃ microdisc arrays and (b) WO₃ film. The images and roughness of samples were obtained using an atomic-force microscopy (AFM, NX20, Park Systems) in non-contact mode. AFM scans were taken over 10 μm × 10 μm areas. The thickness of WO₃ microdisc was around 440 nm, which is well agreed with that estimated with the SEM side view image (Figure S3). The average roughness of WO₃ microdiscs alone was estimated to be 46 nm (R_a) – 66 nm (R_q) because of the central valley of the disc, while that of the entire sample electrode (10 μm × 10 μm) was 96 nm (R_a) – 114 nm (R_q). The roughness of WO₃ film (10 μm × 10 μm) was 4.3 nm (R_a) – 5.7 (R_q). The higher roughness can cause the light-scattering (a negative effect in the absorption) and the re-absorption of the

scattered light (a positive effect in the absorption). These two phenomena can offset or minimize the roughness effect on the overall absorption of WO_3 microdisc arrays.

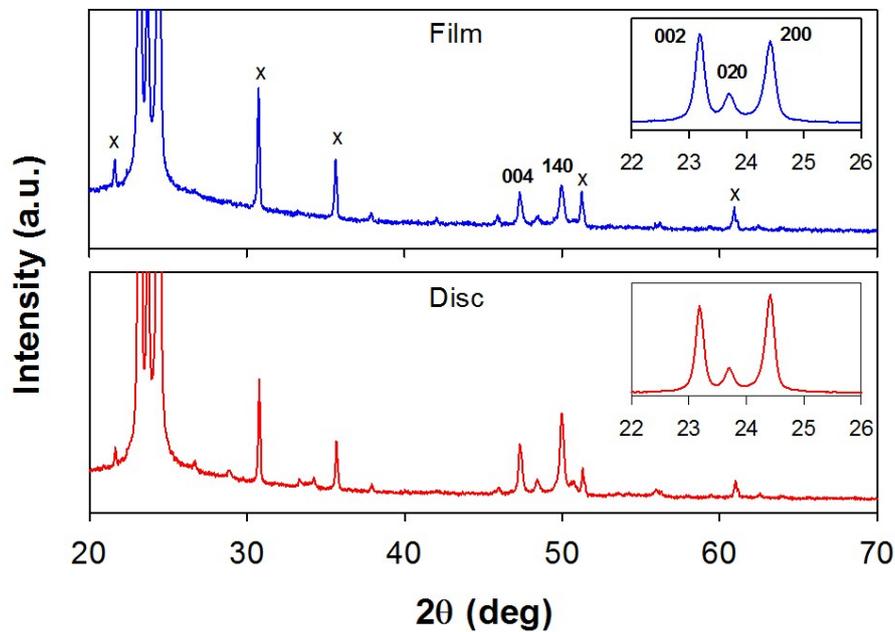


Figure S4. X-ray diffraction patterns of WO_3 film and patterned WO_3 microdisc arrays (x: ITO substrate).

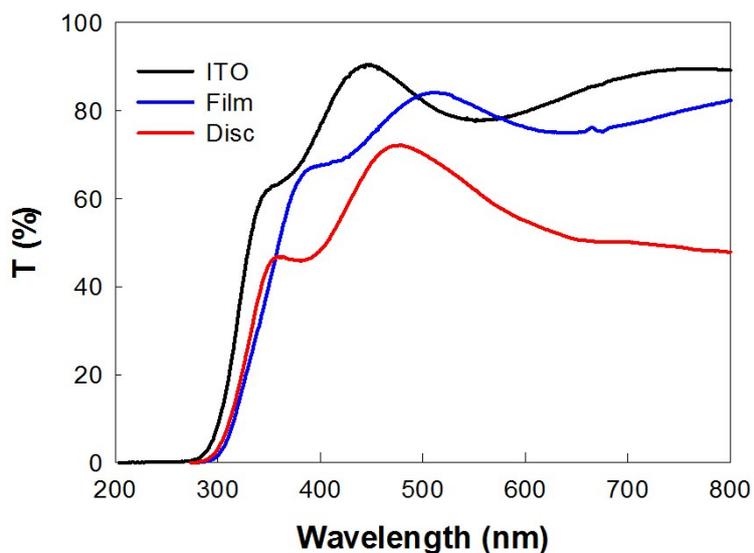
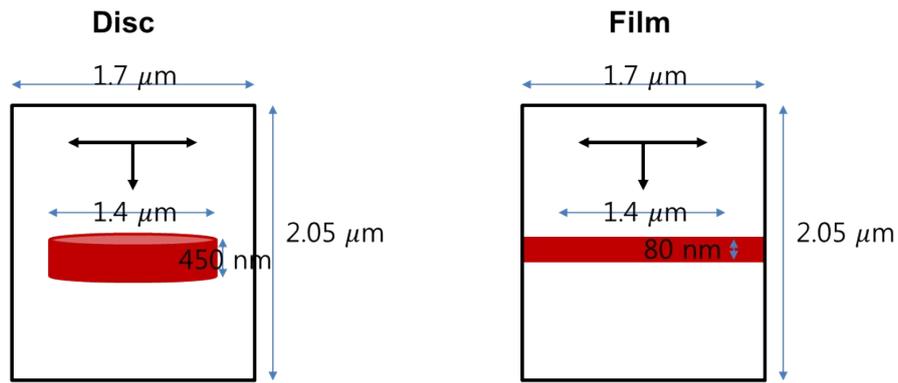


Figure S5. Transmittance of bare ITO substrate, WO_3 film, and patterned WO_3 microdisc arrays.



Source : Plane wave, 350 nm ~ 550 nm
 Boundary condition : Stretched coordinate PML
 Mesh : 4 nm

Figure S6. Geometry comparison of WO_3 microdisc and film, and other parameters for finite-difference time-domain simulation.

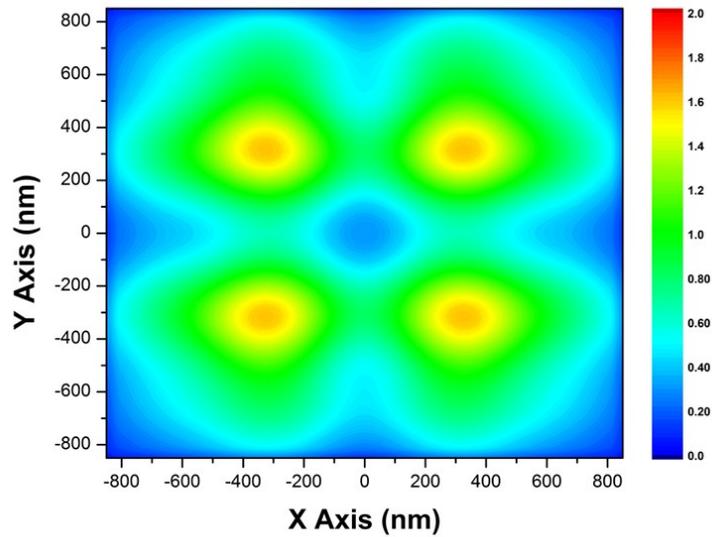


Figure S7. Simulated electric field intensity distribution (top view) for the WO_3 film at 404.7 nm.

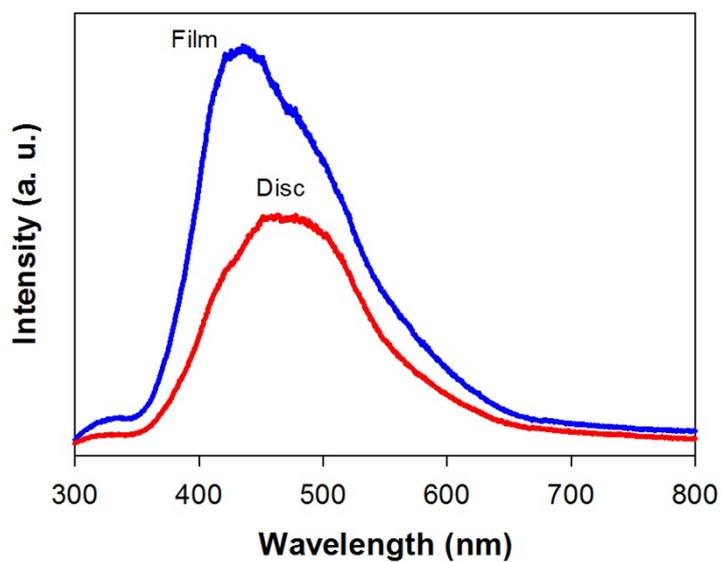


Figure S8. Photoluminescence (PL) emission spectra of WO_3 film and patterned WO_3 microdisc arrays.

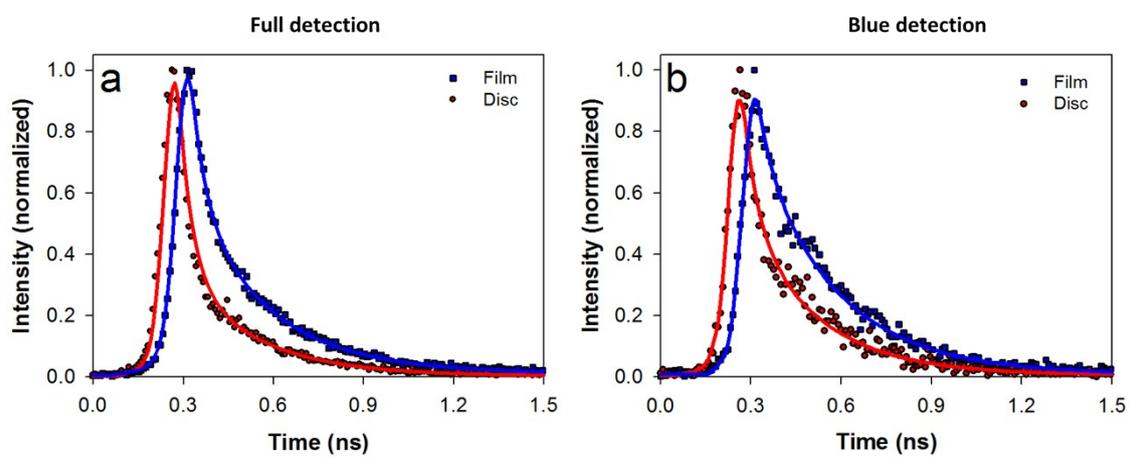


Figure S9. TRPL emission decay of samples (excited at $\lambda = 375$ nm): (a) full range emission and (b) blue emission ($\lambda < 500$ nm).

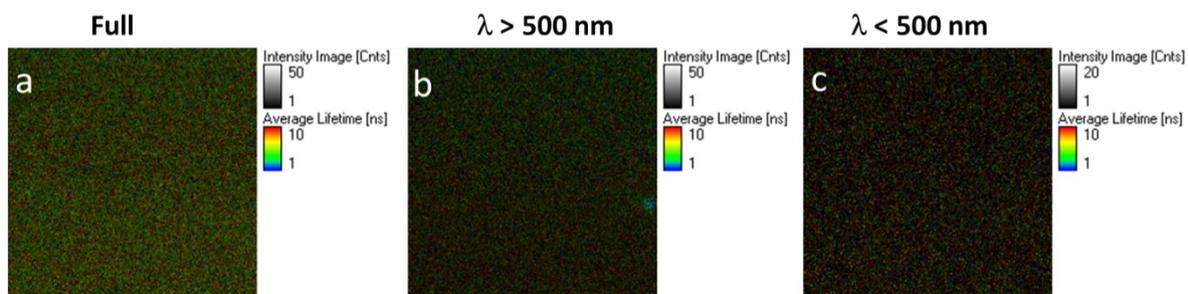


Figure S10. Two-dimensional PL lifetime images for WO₃ film (a: full emission, b: green emission, c: blue emission).

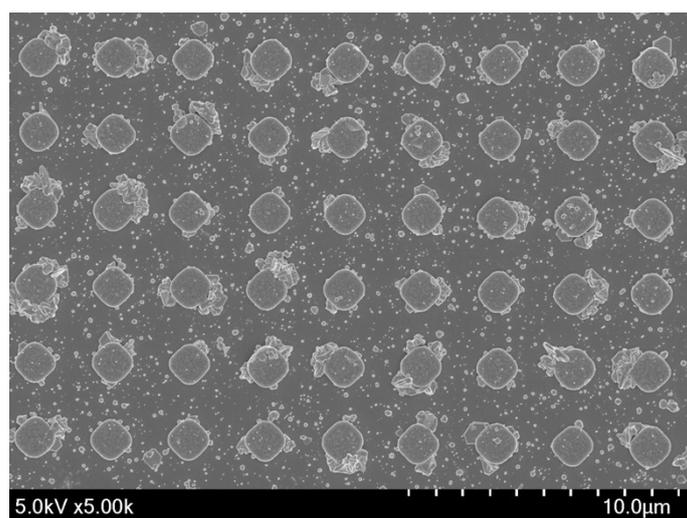


Figure S11. FE-SEM image of Au/WO₃ microdisc arrays prepared by photodeposition of Au for 30 min.

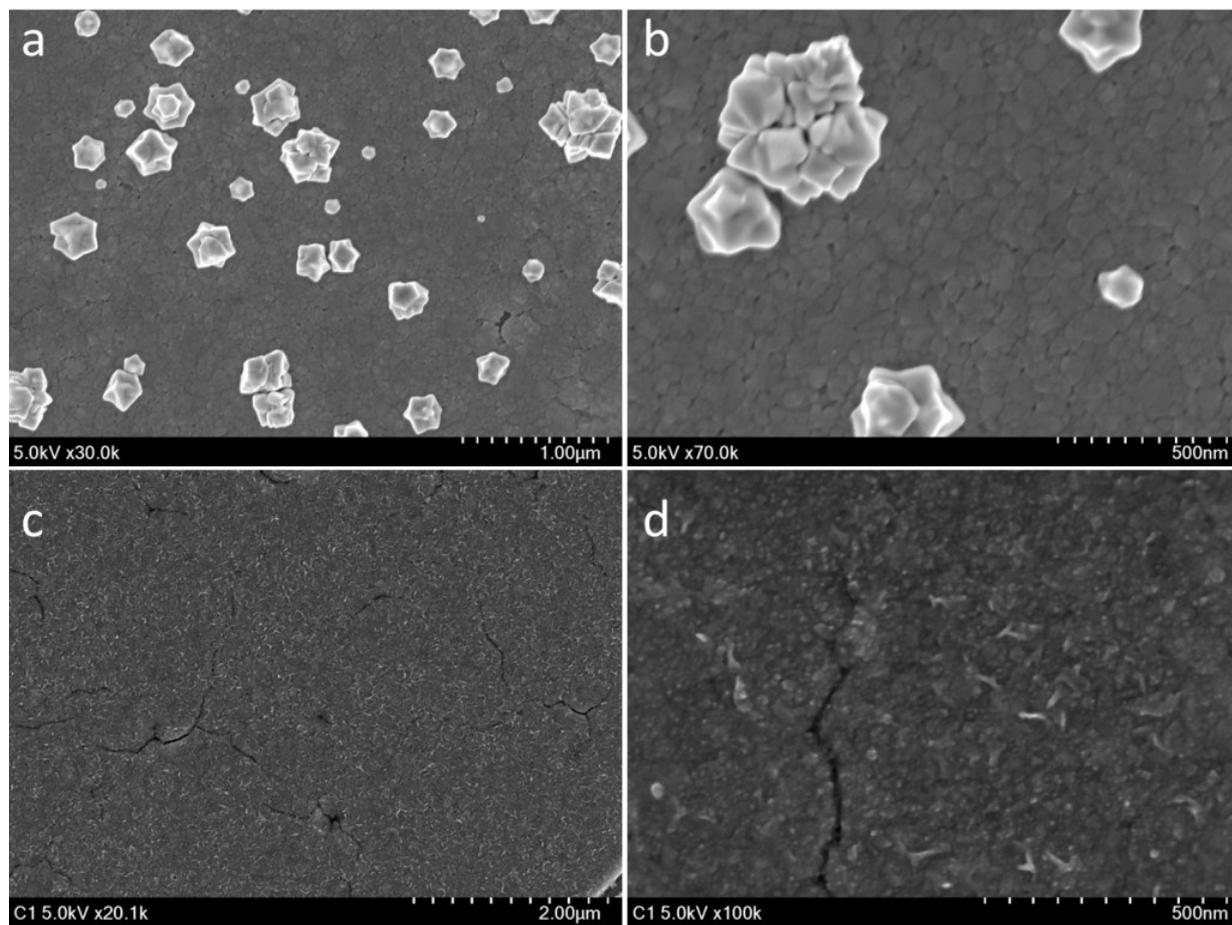


Figure S12. Field-emission scanning electron microscopy images of (a, b) Au/WO₃ film and (c, d) FeOOH/WO₃ film.